

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application Serial No. 09/234,233
Filing Date January 20, 1999
Inventor Weimin Li, et al
Assignee Micron Technology, Inc.
Group Art Unit 2818
Examiner D. Vu
Attorney's Docket No. MI22-1035
Title: Semiconductor Processing Methods

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INFORMATION DISCLOSURE STATEMENT

References – See Attached Form PTO-1449

In compliance with 37 C.F.R. §§ 1.56, 1.97 and 1.98, your attention is directed to the United States patents listed on the attached Form PTO-1449. No admission is made regarding whether all the submitted references are prior art.

This Supplemental Information Disclosure Statement is being filed after the filing of a Request for Continued Examination (RCE) Application and prior to the receipt of the first Office Action. Therefore, no fee is believed to be required. However, in the event that a fee is required for filing this Supplemental Information Disclosure Statement, please charge the fee specified under 37 C.F.R. §1.17(p) to Deposit Account No. 23-0925. Please credit Deposit Account No. 23-0925 with any overpayment of the above fee.

Citation of these references is respectfully requested.

Respectfully submitted,

Dated: 25 Jun 2004

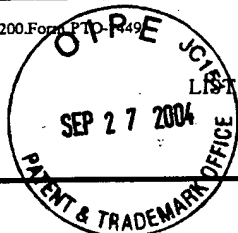
By: _____

James E. Lake
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PATENT AND TRADEMARK OFFICEATTY. DOCKET NO.
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LIST OF ART CITED BY APPLICANT

(Use several sheets if necessary)

APPLICANT
Weimin LiFILING DATE
January 20, 1999GROUP
2818

U.S. PATENT DOCUMENTS

*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	AA	4,971,655	11-90	Stefano et al.			
	AB	6,498,084B2	12-02	Bergemont			
	AC	5,036,383	07-91	Mori			
	AD	6,638,875	10/03	Han et al			
	AE	6,720,247	04/04	Kirkpatrick et al			
	AF	6,723,631	04/04	Noguchi et al			
	AG	6,627,535	09/03	MacNeil et al			
	AH	5,593,741	01/97	Ikeda			
	AI	2003/0077916	04/03	Xu et al			
	AJ	2003/0207594	11/03	Catabay et al			
	AK	2004/0071878	04/04	Schuhmacher et al			

FOREIGN PATENT DOCUMENTS

		Document Number	Date	Country	Class	Subclass	Translation	
							Yes	No
	AL	08-045926A	2/96	Japan				
	AM	JP8051058	02/96	Japan				
	AN	JP63316476	12/88	Japan				
	AO	JP8078322	03/96	Japan				

OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)

	AP		Wolf, S., Silicon Process., Vol. 3 pg. 635
	AQ		
	AR		

EXAMINER

DATE CONSIDERED

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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